	Application No.	Applicant(s)
Nation of Allowshiller	09/677,478	BLALOCK ET AL.
Notice of Allowability	Examiner	Art Unit
	Lan Vinh	1765
The MAILING DATE of this communication appearance All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this ap or other appropriate communication GHTS. This application is subject to	plication. If not included n will be mailed in due course. THIS
1. This communication is responsive to <u>The RCE and respose filed on 6/26/2006</u> .		
2. The allowed claim(s) is/are <u>1-3,6,7,10-13,16-19,21-28,30,32,33,36-42,44,46-48,50 and 53-94</u> .		
3. The drawings filed on <u>02 October 2000</u> are accepted by the Examiner.		
 4. ☐ Acknowledgment is made of a claim for foreign priority una) ☐ All b) ☐ Some* c) ☐ None of the: Certified copies of the priority documents have Certified copies of the priority documents have Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: 	been received. been received in Application No	
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		complying with the requirements
5. A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give		
6. CORRECTED DRAWINGS (as "replacement sheets") mus	st be submitted.	
(a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached		
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date		
(b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date		
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in t		
7. DEPOSIT OF and/or INFORMATION about the depo- attached Examiner's comment regarding REQUIREMENT		
Attach mont(s)		
Attachment(s) 1. ☐ Notice of References Cited (PTO-892)	5. Notice of Informal F	Patent Application (PTO-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. Interview Summary	(PTO-413),
3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 62606 }0/02/00	Paper No./Mail Da 8), 7. 🗌 Examiner's Amenda	te ment/Comment
4. ☐ Examiner's Comment Regarding Requirement for Deposit	8. X Examiner's Stateme	ent of Reasons for Allowance
of Biological Material	9. 🗌 Other	
		Lan Vinh AU 1765

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Continued Examination Under 37 CFR 1.114

1. A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 6/26/2006 has been entered.

Allowable Subject Matter

2. Claims 1-3, 6-7, 10-13, 16-19, 21-28, 30, 32-33, 36-42, 44, 46, 47-48, 50, 53, 54-94 allowed.

The following is an examiner's statement of reasons for allowance:

Regarding claim 1, the applicants have presented a persuasive argument, presented in an interview conducted on 6/23/2006, that the combination of Ding (US 5,814,563) and Sahin (6,465,051) fails to disclose or suggest "wherein the gas comprises O2, and wherein the hydrogen component and 02 are provided in the chamber during the plasma etching at a volumetric ratio of the one to the another of at least 0.1:1 of O2 to the hydrogen component. Thus, the previous final rejection(s) (mailing date 1/26/2006) of claims 1-3,6-7,80-87 based on Ding and Sahin have been withdrawn

Regarding claim 10, the applicants have presented a persuasive argument, presented in an interview conducted on 6/23/2006, that the combination of Ding (US

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5,814,563) and Sahin (6,465,051) fails to disclose or suggest "wherein the gas comprises a gas comprises an oxygen component forming an oxygen and carbon compound mixture, and wherein the carbon compound is provided at from about 5% to about 80% by volume of the oxygen and carbon compound mixture". Thus the previous final rejection(s) (mailing date 1/26/2006) of claims 10-13,16-19, 81, 88 based on Ding and Sahin have been withdrawn

The reason(s) for allowance of claims 21, 59 have been stated in the previous office action (paper 030604)

Regarding claim 36, the cited prior art of record fail to disclose or suggest a step of 'after the first plasma etching and with the wafer on the wafer receiver, second plasma etching at subatmospheric pressure using a gas having one or more components effective to etch photoresist from the wafer and polymer from chamber internal surface and getter halogen liberated from the polymer to restrict further etching of the material on the semiconductor wafer during the second plasma etching, the gas having the one or more components comprising at least H2 and CH4, in combination with the rest of the limitations of claim 36

Regarding claims 47, 54-57, 84-85, 91-92, the applicants have presented a persuasive argument, presented in an interview conducted on 6/23/2006, that Ding (US 5,814,563) does not teach or suggest a second plasma etching. Thus the final previous rejection(s) (mailing date 1/26/2006) of claims 47, 53, 54-57 based on Ding have been withdrawn

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Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

3. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Lan Vinh whose telephone number is 571 272 1471. The examiner can normally be reached on M-F 8:30-5:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine Norton can be reached on 571 272 1465. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

LV

August 17, 2006